

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	0	(716/21).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:17
L2	1	(716/19).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:22
L3	0	(716/21).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:22
L4	1	("716"/\$).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:22
L5	2	((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:22
L6	2	((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function) and (parametric adj yield)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:25
L7	1	((((mask adj design) same layout) and (resolution adj enhancement) and (correction same cost) and ((probability adj density) adj function) and (parametric adj yield)).CLM.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:23
L8	1	(716/19).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (toler\$5 same variation) and ((critical dimension) or CD) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:29

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L9	0	(716/21).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (toler\$5 same variation) and ((critical dimension) or CD) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:29
L10	1	("716"/\$).ccls. and ((mask adj design) same layout) and (resolution adj enhancement) and (toler\$5 same variation) and ((critical dimension) or CD) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:29
L11	2	((mask adj design) same layout) and (resolution adj enhancement) and (toler\$5 same variation) and ((critical dimension) or CD) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:30
L12	2	((mask adj design) same layout) and (resolution adj enhancement) and (toler\$5 same variation) and ((critical adj dimension) or CD) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:32
L13	2	((mask adj design) same layout) and (resolution adj enhancement) and ((toler\$5 same variation) same ((critical adj dimension) or CD)) and (((edge adj placement) adj error) or EPE) and correct\$3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:35
L14	1	(((mask adj design) same layout) and (resolution adj enhancement) and ((toler\$5 same variation) same ((critical adj dimension) or CD)) and (((edge adj placement) adj error) or EPE) and correct\$3).CLM.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:33
L15	1	((mask adj design) same layout) and (parametric adj yield) and (mathematical adj (program or equation or expression)) and (correction)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:37
L16	1	((mask adj design) same layout) and (resolution adj enhancement) and (parametric adj yield) and ((selling adj point) same delay)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:39

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L17	2	((mask adj design) same layout) and ((probability adj density) adj function) and (parametric adj yield)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:41
L18	1	((((mask adj design) same layout) and ((probability adj density) adj function) and (parametric adj yield)).CLM.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:41
S1	943	716/21	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 13:13
S2	1295	716/19	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/07/21 12:13

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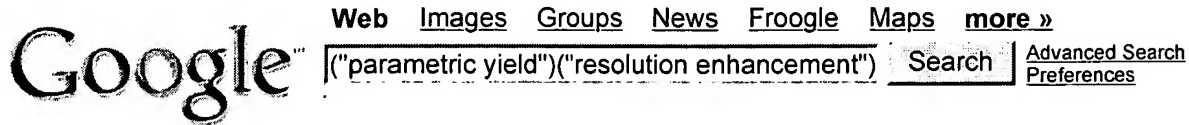
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